

## EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	4	"2001077041"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/03/10 09:35
L4	782	(sakamoto or suzuki or wang or yonekawa or ikeuchi or sato).in. and (test or dummy) (wafer or object)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/03/10 10:29
L5	27	4 and (set\$3 with temperature) and (measur\$3 with thickness)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/03/10 10:30
L6	36	((test or dummy or first or second) (wafer or substrate or object) and measur\$3 and thickness and set\$3 and temperature). clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/03/10 10:40
L13	40	(test or dummy) (wafer or substrate) with (bare and oxide)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/03/10 13:00
L14	7	5 and (convey\$3 or wafer-convey\$3 or arm or cassette or cassette-convey\$3 or wafer-cassette)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/03/10 15:16

3/10/2009 4:41:20 PM

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\10523803.thermal processing multiple substrates.wsp